Amendments to the Claims. C.

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- 33. (Currently Amended) A random access memory cell, comprising:
 - a data storage node; and
 - a pass transistor coupled to the data storage node to provide charge transfer to and from the data storage node and including
 - a source region,
 - a drain region,
- a channel region disposed between the source region and the drain 10 region, the channel region including a first channel side and a second channel side opposite to the first channel side,
 - a first channel side control gate, and
 - a second channel side control gate wherein
 - the first channel side control gate is formed in a trench.
 - 34. (Previously Presented) The random access memory cell of claim 33, further including:
- a substrate insulator layer providing electrical isolation between the first channel side control gate and a substrate. 20
 - 35. (Previously Presented) The random access memory cell of claim 33, further including:
- a first channel side gate insulating layer disposed between the first channel side control gate and the first channel side. 25

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- 36. (Previously Presented) The random access memory cell of claim 35, wherein:
 the first channel side gate insulating layer include thermally grown silicon dioxide.
- 37. (Previously Presented) The random access memory cell of claim 33, wherein: the first channel side control gate includes doped polysilicon.

- 38. (Previously Presented) The random access memory cell of claim 33, wherein:

 a second channel side gate insulating layer disposed between the second channel side control gate and the second channel side.
- 39. (Previously Presented) The random access memory cell of claim 38, wherein:

 the second channel side gate insulating layer include thermally grown
 silicon dioxide.
 - 40. (Previously Presented) The random access memory cell of claim 33, wherein: the data storage node includes polysilicon.
- 41. (Currently Amended) The random access memory cell of claim 33, wherein:

 the first channel side control gate and the second channel control side

 gate are electrically connected to a word line; and

 the word line is electrically connected to a word line driver.
- 25 42. (Previously Presented) The random access memory cell of claim 33, wherein:

the data storage node is a first terminal of a storage capacitor.

43. (Previously Presented) The random access memory cell of claim 42, wherein: the storage capacitor includes a capacitor dielectric layer including nitride.

- 44. (Previously Presented) The random access memory cell of claim 42, wherein: the storage capacitor includes a capacitor dielectric layer including Si₃N₄.
- 45. (Previously Presented) The random access memory cell of claim 42, wherein: the storage capacitor includes a capacitor dielectric layer including Ta2O5.
- 46. (Previously Presented) The random access memory cell of claim 42, wherein: 10 the storage capacitor includes a capacitor dielectric layer including SrTiO₃.
 - 47. (Previously Presented) The random access memory cell of claim 42, wherein: the storage capacitor includes a capacitor dielectric layer including BaSrTiO₃.
 - 48. (Previously Presented) The random access memory cell of claim 42, wherein: the storage capacitor includes a second terminal shared with at least another storage capacitor of another random access memory cell.
 - 49. (Previously Presented) The random access memory cell of claim 42, wherein: the storage capacitor is a trench capacitor.
 - 50. (Previously Presented) The random access memory cell of claim 42, wherein: the storage capacitor has a capacitor-over-bit line structure.
- 51. (Previously Presented) The random access memory cell of claim 42, wherein: 15

the storage capacitor has a capacitor-under-bit line structure.

- 52. (Previously Presented) The random access memory cell of claim 33, wherein:

 the pass transistor is coupled to provide charge transfer between the storage node and a bit line; and

 the bit line includes metal from the group consisting of Ti, Al, and Cu.
- 53. (Currently Amended) The random access memory cell of claim 33 34, wherein: the trench is at least partially defined by the substrate insulator layer.

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